Sheet Loft

Porm PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OPFICE LIST OF ART CITED BY APPLICANT			ATTY, DOCKET NO. MIZZ-2315 APPLICANT			SERIAL NO. 10/635,715		
		(Use several shoots if necessary)			Winston G. Scott PILING DATE		-		·	
	<u> </u>		<u></u>		August 5, 2003	·	Usb			
				U.S. PATENT DOCUMENTS	······································	,				
*Pannionr Initial		Document Number	Date	Name		Class	Subélaza	Filing If Appr	Date opriate	
	AĄ									
-	EA						<u></u>			
	AC									
	AD									
	AE									
	AF									
	AG									
	AH					:				
	Aĵ				·					
	. AI	·								
	AK									
	AL									
			7	POREIGN PATENT DOCUMEN	TS					
ļ		Document Number	Date	Country		Class	Subclass	Trant Yes	lutios ·	
	·AM									
	AN				· · · · · · · · · · · · · · · · · · ·		·			
	AO AP									
	<u> </u>	0	THER REFEREN	CES (including Author, Thie, Date	, Pertiaant Pages, Etc.)			L	
AR Wolf, S., "Silicon Processing for the VLST Ets", Vol. 1: Process Technology, 1986 Lattice Press, pp. 434-437.										
11/2							······································			
	AS						*****		:	
										
	AT				, , , , , , , , , , , , , , , , , , , 	·				
					·					
EXAMINER	lu	hand a	4	DATE CONSIDER	O3	7/5	1/5	<u> </u>		
EXAMINER		I reference considered wi	other or not clean	tion is in conformance with MPE	F 609: Draw line shre	sigh gimilar	if not in an	plarmance and	d not	

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET I MI22-2375		PRIORITY SERIAL NO. 09/876,722				
LIST OF ART CITED (Use several sheets											
(030.30.418) 30660							PRIORITY GROUP 2812				
U.S. PATENT DOCUMENTS											
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate			
11/2	АА	6,033,952	03/00	Yasumura et al.							
	AB	6,124,168	9/2000	Ong							
	AC	5,668,705	11/97	Bergemont							
	AD	5,866,448	2/99	Pradeep et al.							
110	ΑE	5,858,847	1/99	Zhou et al.							
	AF										
	AG										
	АН										
	Al	·			<u></u>						
	ک										
	AK										
	Al.								$ \bot $		
				FOREIGN PATENT DOCUMEN	175		·····	·			
		Document Number	Date	Country	Country		Subclass	Translation Yes No			
	414					 		Yes	-		
	AM AN										
	AO										
	AP										
		от	HER REFEREN	CES (including Author, Title, Dat	e, Pertinent Pages, Etc.	.)			-		
NA	AR Watanabe, H. et al., "Novel 0.44µm² Ti-Salicide STI Cell Technology for High-Density NOR Flash Memories and High Perfo										
Up.		Embedded App	Embedded Application", IEEE 1998, pp. 36.2.1 - 36.2.4.								
NA	AS	Wolf, S., "Silicon	Wolf, S., "Silicon Processing for the VLSI Era", Vol. 2, pp. 632-635.								
1119											
11	AT	MITSUBISHI ELE	MITSUBISHI ELECTRIC WEBSITE: Reprinted from website http://www.mitsubishielectric.com/r and d/tech showcase/ks8.php on								
/lf/		3/29/2001: "8. [3/29/2001: "8. Production Line Application of a Fine Hole Pattern-Formation Technology for Semiconductors", on 3/29/2001, 4 pgs.								
EXAMINER DATE CONSIDERED 31/2/55											
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.											
<u> </u>	TOWNSELECT. INCIDENT TOWN INTO THAT TOWNSELECT TO SPECIAL TOWNSELECT.										

Form PTO-14	49	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-2375			PRIORITY SERIAL NO. 09/876,722			
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Winston G. Scott						
, in the second					PRIORITY FILING 6/6/01	PR10 2812	PRIORITY GROUP 2812				
				U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate			
	AA										
	AB										
	AC										
	AD										
	AE								<u> </u>		
	AF				_		-		- · · · · · · · · · · · · · · · · · · ·		
	AG										
	AH										
	Al		-								
	ΑJ				·						
	AK		:								
	AL										
				FOREIGN PATENT DOCUMEN	rrs	li		_	9		
		Document	Date	Country		Class	Subclass	Trans	lation		
		Number						∕ Yes	No		
	AM		ļ. -								
	AN										
	AO		 					-			
	ΑP	L	I					L	L		
				CES (including Author, Title, Date							
NA	AR CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from http://www.semiconductor.net/semi							niconductor/is	sues/		
110			1999/sep99/docs/feature1.asp on 3/29/2001: "Resists Join the Sub-λ Revolution", 9 pgs.								
n.	A\$	CAHNERS SEMI	CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from http://www.semiconductor.net/semiconductor/issues/								
1.117		1999/aug99/docs/lithography.asp on 3/29/2001: "Paths to Smaller Features", 1 pg.									
	AT								~~~~		
EXAMINER Modern AT DATE CONSIDERED D3/17/60											
	*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.										